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Docket No.: 1514.1032

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of:

PARK, Ji Yong et al.

Serial No. 10/690,507

Group Art Unit: 1765

Confirmation No. 6043

Filed: October 23, 2003

Examiner: Unassigned

For: METHOD FOR MANUFACTURING POLYCRYSTALLINE SILICON THIN FILM AND  
THIN FILM TRANSISTOR FABRICATED USING POLYCRYSTALLINE SILICON THIN  
FILM MANUFACTURED BY THE MANUFACTURING METHOD

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

Sir:

Before examination of the above-identified application, please amend the application as follows:

**IN THE TITLE:**

Please DELETE the Title in its entirety and substitute the attached new Title.

METHOD FOR MANUFACTURING POLYCRYSTALLINE SILICON THIN FILM AND  
THIN FILM TRANSISTOR FABRICATED USING POLYCRYSTALLINE SILICON THIN FILM  
MANUFACTURED BY THE MANUFACTURING METHOD